Please amend the subject application as follows:

IN THE CLAIMS

Amend claim(s) 1-2, 13-14, 16 and 17 to read as follows:

1. (THRICE AMENDED) A mechanism for supporting a substrate to be coated with a film, which mechanism is used in a film forming apparatus, comprising:

a stage for receiving a substrate which has been transported into the film forming apparatus to form a film on the substrate;

a shaft member for angularly displacing the stage, that is bearing the substrate, from a substrate receiving position at which the stage received the substrate, to a film forming position at which a substrate bearing surface of the stage is vertical or substantially vertical;

a plurality of support members which are provided so as to protrude from the substrate bearing surface of the stage and being arranged thereon so as to support only one end surface of the substrate, where said one end surface is the surface which faces downwards when the stage is angularly displaced to the film forming position; and

moving means for moving the support members.

2. (TWICE AMENDED) A mechanism for supporting a substrate to be coated with a film, which mechanism is used in a film forming apparatus, comprising:

a stage for receiving a substrate which has been transported into the film forming apparatus to form a film on the substrate;

a shaft member for angularly displacing the stage, that is bearing the substrate, from a substrate receiving position at which the stage received the substrate, to a film

forming position at which a substrate bearing surface of the stage is vertical or substantially vertical;

a plurality of support members which are provided so as to protrude from the substrate bearing surface of the stage, and being arranged so as to support only one end surface of the substrate, where said one end surface is the surface which faces downwards, when the stage is angularly displaced to the film forming position;

moving means for moving the support members; and

wherein the moving means causes the support members to move in parallel in one direction of three dimensional directions on the stage or causes the support members to rotationally move on the stage.

13. (AMENDED) The mechanism for supporting a substrate to be coated with the film of claim 1, wherein each of the plurality of support members has a long axis that extends from the substrate bearing surface and wherein the moving means is configured and arranged so as to cause the support members to move in one direction with respect to a plane in which lies the long axis of each of the support members.

14. (AMENDED) The mechanism for supporting a substrate to be coated with the film of claim 1, wherein each of the plurality of support members has a long axis that extends from the substrate bearing surface and wherein the moving means is configured and arranged so as to cause the support members to move in a direction generally perpendicular to a plane in which lies the long axis of each of the support members.

16. (AMENDED) The mechanism for supporting a substrate to be coated with the film of claim 1, wherein each of the plurality of support members has a long axis that extends from the substrate bearing surface and wherein the moving means is configured and arrange so as to cause each of the support members to rotate about the long axis of each support member.

17. (AMENDED) A mechanism for supporting a substrate to be coated with the film, which mechanism is used in a film forming apparatus, comprising:

a stage for receiving a substrate which has been transported into the film forming apparatus to form a film on the substrate;

a shaft member for angularly displacing the stage, that is bearing the substrate, from a substrate receiving position at which the stage received the substrate, to a film forming position at which a substrate bearing surface of the stage is vertical or substantially vertical;

a plurality of support members which are provided so as to protrude from the substrate bearing surface of the stage and to support only one end surface of the substrate, where said one end surface is the surface which faces downwards when the stage is angularly displaced to the film forming position, each of the plurality of support members having a long axis that extends from the substrate bearing surface;

moving means for moving the support members; and